

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: )  
Shinji MAEKAWA et al. ) Group Art Unit: 2812  
Application No. 10/575,492 ) Examiner: Stanetta D. Isaac  
Filed: April 12, 2006 ) Confirmation No. 3788  
  
For: METHOD FOR FORMING WIRING, METHOD )  
FOR MANUFACTURING THIN FILM  
TRANSISTOR AND DROPLET DISCHARGING  
METHOD

**REQUEST FOR ACKNOWLEDGMENT OF  
INFORMATION DISCLOSURE STATEMENT**

MAIL STOP ISSUE FEE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

An Information Disclosure Statement (IDS) with Form PTO-1449 was filed in the above-identified patent application on June 30, 2011 (copies of which are attached). This IDS was corrected relative to the U.S. patent documents on July 9, 2010. The Examiner considered the corrected U.S. patent documents filed in the corrected IDS of July 9, 2010, but has failed to consider the Foreign patent documents filed on June 30, 2010.

The Examiner is requested to initial and return to the undersigned a copy of the subject Form PTO-1449 to acknowledge consideration of the Foreign patent documents. It is requested that the Examiner mark through the U.S. patent documents since these have been corrected and considered previously.

Should there be any questions concerning this communication, please telephone the undersigned at the number set forth below.

Respectfully submitted,

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